

☒ L4: (0) 2 and (substrate a
☒ L6: (0) 2 and (substrate a
☒ L7: (25) 2 and (electromag
☒ L5: (21) 2 and (substrate
☒ L8: (862) 2 and 'MEMS'
☒ L9: (477) 8 and (actuator

Failed

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DBs: USPAT; EPO; JPO

☒ Plurals

Default operator:

☒ Highlight all hit terms initial

8 and (actuator and substrate)

 BRS f...  IS&R ...  Image  Text  HTML

	U	1	Document ID	Issue Date	Pages	Title	Current OR	Current XRef
1	<input type="checkbox"/>	<input type="checkbox"/>	US 6563238 B1	20030513	14	Comb structure using magnetic force and actuator	310/15	
2	<input type="checkbox"/>	<input type="checkbox"/>	US 6563184 B1	20030513	21	Single crystal tunneling sensor or switch with	257/419	257/254; 257/415;
3	<input type="checkbox"/>	<input type="checkbox"/>	US 6563133 B1	20030513	24	Method of epitaxial-like wafer bonding at low	257/52	257/347; 257/618;
4	<input type="checkbox"/>	<input type="checkbox"/>	US 6563106 B1	20030513	23	Micro-electro-mechanical-system (MEMS) mirror device and	250/216	250/208.1; 359/291
5	<input type="checkbox"/>	<input type="checkbox"/>	US 6562523 B1	20030513	56	Direct write all-glass photomask blanks	430/5	430/13; 430/296;
6	<input type="checkbox"/>	<input type="checkbox"/>	US 6562000 B2	20030513	18	Single-use therapeutic substance delivery device	604/48	604/132; 604/67
7	<input type="checkbox"/>	<input type="checkbox"/>	US 6561725 B1	20030513	19	System and method for coupling microcomponents	403/326	24/453; 24/625;
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6561627 B2	20030513	12	Thermal actuator	347/54	347/56
9	<input type="checkbox"/>	<input type="checkbox"/>	US 6561224 B1	20030513	13	Microfluidic valve and system therefor	137/831	137/827; 251/129.06;
10	<input type="checkbox"/>	<input type="checkbox"/>	US 6560384 B1	20030506	8	Optical switch having mirrors arranged to	385/18	385/16; 385/17
11	<input type="checkbox"/>	<input type="checkbox"/>	US 6559550 B2	20030506	12	Nanoscale piezoelectric generation system using	290/1R	